

Professor M.Esashi was awarded "the Achievement Award by the Laser Society of Japan".

Development of Pulse Laser Assisted Debris-Free Low-Stress Dicing for Multi-Layered MEMS

(Masayuki Fujita, Kiichi Sueta, Yoshiki Nakata, Noriaki Miyanaga, Hideyuki Fukushi, Masayoshi Esashi, Shuji Tanaka)

The award was given to the following three contributions in The Laser

Society.(1)"Development of Pulse Laser Assisted Debris-Free Low-Stress Dicing for Multi-Layered MEMS",RTM-07-53, The 369th of Laser Society, Tokushima (Dec.17, 2007)

(2)"Development of Pulse Laser Assisted Debris-Free Low-Stress Dicing for Multi-Layered MEMS",1aVI-3The 28th Annual Convention of Laser Society, Nagoya (Feb.1, 2008)

(3)"Development of Pulse Laser Assisted Low-Stress Dicing for Multi-Layered MEMS", 10pIV-6, The 29th Annual Convention of Laser Society, Tokushima (Jan.10,2009)